(12) INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(19) World Intellectual Property Organization

International Bureau



(43) International Publication Date 25 November 2004 (25.11.2004)

PCT

(10) International Publication Number $WO\ 2004/102648\ A3$

(51) International Patent Classification⁷: **H01L 21/285**, C23C 16/44, C30B 25/00

(21) International Application Number:

PCT/US2004/013166

(22) International Filing Date: 29 April 2004 (29.04.2004)

(25) Filing Language: English

(26) Publication Language: English

(**30**) Priority Data: 60/469,181

9 May 2003 (09.05.2003) US

(71) Applicant (for all designated States except US): ASM AMERICA, INC. [US/US]; 3440 East University Drive, Phoenix, Arizona 85034-7200 (US).

(72) Inventors; and

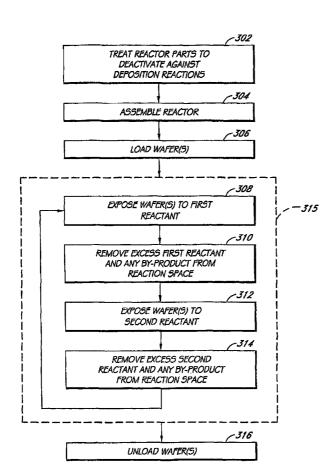
(75) Inventors/Applicants (for US only): VERGHESE, Mohith [IN/US]; 6102 N. 22nd Drive, Phoenix, Arizona 85015

(US). **SHERO, Eric, J.** [US/US]; 3820 N. 30th Street, Phoenix, Arizona 85016 (US).

- (74) Agent: DELANEY, Karoline, A.; 2040 Main Street, Fourteenth Floor, Irvine, California 92614 (US).
- (81) Designated States (unless otherwise indicated, for every kind of national protection available): AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW.
- (84) Designated States (unless otherwise indicated, for every kind of regional protection available): ARIPO (BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW), Eurasian (AM, AZ, BY, KG, KZ, MD, RU, TJ, TM),

[Continued on next page]

(54) Title: REACTOR SURFACE PASSIVATION THROUGH CHEMICAL DEACTIVATION



(57) Abstract: Protective layers (208) are formed on a surface (201) of an atomic layer deposition (ALD) or chemical vapor deposition (CVD) reactor (100). Parts defining a reaction space (200) for an ALD or CVD reactor (100) can be treated, in situ or ex situ, with chemicals (206) that deactivate reactive sites (210) on the reaction space surface(s) (201). A pre-treatment step (502) can maximize the available reactive sites (210) prior to the treatment step (504). With reactive sites (210) deactivated by adsorbed treatment reactant (208), during subsequent processing the reactant gases (214) have reduced reactivity or deposition upon these treated surfaces. Accordingly, purge steps (310, 314) can be greatly shortened and a greater number of runs can be conducted between cleaning steps to remove built-up deposition on the reactor walls.

WO 2004/102648 A3



European (AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR), OAPI (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG).

Published:

with international search report

(88) Date of publication of the international search report: 24 March 2005

For two-letter codes and other abbreviations, refer to the "Guidance Notes on Codes and Abbreviations" appearing at the beginning of each regular issue of the PCT Gazette.

INTERNATIONAL SEARCH REPORT

International Application No ,__./US2004/013166

Relevant to claim No.

A. CLASSIFICATION OF SUBJECT MATTER IPC 7 H01L21/285 C23C16/44 C30B25/00

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal, WPI Data, PAJ, COMPENDEX, CHEM ABS Data, INSPEC

Citation of document, with indication, where appropriate, of the relevant passages

X A	WO 02/088421 A (APPLIED MATERIAL 7 November 2002 (2002-11-07) paragraphs '0004!, '0021!; figu	1,2,6,7, 17,18 30		
х	WO 01/27346 A (ASM MICROCHEMISTR 19 April 2001 (2001-04-19)	Y 0Y)	1-4,6, 17,18, 23,24	
Υ [example 1		5	
Y	WO 01/40541 A (ASM MICROCHEMISTR 7 June 2001 (2001-06-07)		5	
Α	page 6, line 1 - page 9, line 27 claim 6; example 1		15	
A	EP 0 844 028 A (NANOFILM CORP) 27 May 1998 (1998-05-27) column 6, line 44 - column 8, li	ne 6	10-16	
		-/		
X Furth	ner documents are listed in the continuation of box C.	Patent family members are listed in	n annex.	
° Special cal 'A' docume consid 'E' earlier difiling d 'L' docume which i citation 'O' docume other n 'P' docume later th	rnational filing date the application but every underlying the laimed invention be considered to cument is taken alone laimed invention ventive step when the ore other such docu- us to a person skilled family			
Date of the a	actual completion of the international search	Date of mailing of the international search report		
19	9 October 2004	28/10/2004		
Name and m	nailing address of the ISA European Patent Office, P.B. 5818 Patentlaan 2 NL – 2280 HV Rijswijk Tel. (+31-70) 340-2040, Tx. 31 651 epo nl, Fax: (+31-70) 340-3016	Authorized officer Hoyer, W		

Form PCT/ISA/210 (second sheet) (January 2004)

INTERNATIONAL SEARCH REPORT

national Application No

| TUS2004/013166

C.(Continu	ation) DOCUMENTS CONSIDERED TO BE RELEVANT	
Category °		Relevant to claim No.
A	US 4 539 061 A (SAGIV JACOB) 3 September 1985 (1985-09-03) column 2, lines 20-66 column 3, lines 26-38 column 11, lines 31-62; tables III,IV	13,14, 20-22
E	column 3, lines 26-38 column 11, lines 31-62; tables III,IV WO 2004/063421 A (MICRON TECHNOLOGY INC) 29 July 2004 (2004-07-29) page 7, column 1 - page 13, column 8	1-3,17,

INTERNATIONAL SEARCH REPORT

Information on patent family members

----ational Application No

_							
	atent document d in search report		Publication date		Patent family member(s)		Publication date
WO	02088421	Α	07-11-2002	US	2002162507	A1	07-11-2002
	·			WO	02088421		07-11-2002
WO	0127346	A	19-04-2001	FI	992233		16-04-2001
				AU	1088401		30-04-2001
				AU	1208201		30-04-2001
				AU	7925700		23-04-2001
				EP	1230421		14-08-2002
				EP	1221178		10-07-2002
				MO	0127346		19-04-2001
				FI	20000564		16-04-2001
				JP	2003511560	Ţ	25-03-2003
				JP		Ţ	19-08-2003
				JP	2003512527		02-04-2003
				TW	500826		01-09-2002
				WO	0129280		26-04-2001
				WO	0129893 6767582		26-04-2001
				US US			27-07-2004
				US	2002187256 2003031807		12-12-2002 13-02 - 2003
				US	6482262		19-11-2002
				US	6475276		05-11-2002
WO	0140541	Α	07-06-2001	FΙ	992616		04-06-2001
				AU	2374301		12-06-2001
				EP	1248865		16-10-2002
				MO	0140541		07-06-2001
				JP	2003515674	Ţ	07-05-2003
				US	2003188682		09-10-2003
				US 	2004065253 		08-04-2004
EP	0844028	Α	27-05-1998	US	5766698		16-06-1998
				CA	2217576		25-05-1998
				CA	2474828		25-05-1998
				DE	69725538		20-11-2003
				DE	69725538		29-07-2004
				EP	1334779		13-08-2003
				EP	0844028		27-05-1998
				US 	5897918 	A 	27-04-1999
	4539061	Α	03-09-1985	NONE			
US 							
	2004063421	Α	29-07-2004	US	2004134427 2004063421		15-07-2004